

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Trung T. Doan

Serial No.:

Filed: August 31, 2000

For: CHEMICAL DISPENSING SYSTEM FOR  
SEMICONDUCTOR WAFER PROCESSING

§  
§ Group Art Unit:  
§  
§ Examiner:  
§  
§ Atty. Docket: 93-0421.04  
§  
§  
§  
§  
§

2/A  
C.7  
10/26/00

PRELIMINARY AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

"EXPRESS MAIL" MAILING LABEL NO. EL003000472US

DATE OF DEPOSIT 8-31-00

I HEREBY CERTIFY THAT THIS PAPER IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE "EXPRESS MAIL POST OFFICE TO ADDRESSEE" SERVICE UNDER 37 C.F.R. § 1.10 ON THE DATE INDICATED ABOVE AND IS ADDRESSED TO THE ASSISTANT COMMISSIONER FOR PATENTS, WASHINGTON, D.C. 20231.

*[Signature]*  
Signature

After awarding the above-captioned application the benefit of the priority date of its great grandparent -- application #08/618,072, filed February 27, 1996 -- please amend the current application as follows.

IN THE SPECIFICATION:

Immediately after the title, please add the following:

Related Applications

A1  
This application is a divisional of pending U.S. Application Ser. No. 09/133,989, filed Aug. 14, 1998; which is a continuation of U.S. Application Ser. No. 08/944,135, filed on October 6, 1997 and issued as U.S. Patent No. 5,952,050; which is a continuation of U.S. Application Ser. No. 08/618,072, filed Feb. 27, 1996 and now abandoned.